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- **52**. The rotating device of claim **51** further comprising a feedback mechanism coupled to said capacitance sensor and said biasing element.
- **53.** The rotating device of claim **50** further comprising a voltage source coupled between said second comb fingers 5 and said first comb fingers.
- **54**. The rotating device of claim **53** further comprising a position sensor to sense the position of the rotating element.
- 55. The rotating device of claim 54, further comprising a feedback mechanism coupled between the position sensor 10 and voltage source.
- **56**. The rotating device of claim **54**, wherein the position sensor includes one or more of the following:

one or more gap closing electrodes,

- a second plurality of first comb fingers coupled to the rotating element and a second plurality of second comb fingers that interdigitate with the first comb fingers in the second plurality,
- a capacitance sensor coupled between the first plurality of first comb fingers and the first plurality of second comb fingers
- a piezoresistive strain gauge,

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- a piezoelectric sensor, or an optical sensor.
- 57. The rotating device of claim 50 wherein said biasing element produces a time-varying biasing force.
- **58**. The rotating device of claim **50** wherein said biasing element produces a constant biasing force.
 - 59. The rotating device of claim 31, further comprising:
 - e) a frame having a third structure coupled to the rotatable flexure:
 - f) a plurality of third comb fingers extending from the third structure
 - g) a second rotatable flexure coupled to the frame such that the frame can rotate about a second axis;
 - h) a plurality of fourth comb fingers coupled to a fourth structure, wherein said third comb fingers are selfaligned and interdigitated with said fourth comb fingers in an engagement.
- **60**. The device of claim **59**, wherein the device is employed in an optical switch.

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